

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	6	displacement with ((laser adj oscillator) or (CCD)) with shape and surface and semiconductor	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 10:58
L2	21	displacement with ((laser adj oscillator) or (CCD)) and shape and surface and (semiconductor adj wafer) and differential	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 10:59
L3	13	displacement with ((laser adj oscillator) or (CCD)) and shape and surface and (semiconductor adj wafer) and differential and ((evaluate) or (evaluation) or (evaluating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:14
L4	595	702/155	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:01
L5	1456	702/150	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:01
L6	2307	702/182	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:02
L7	2208	702/183	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:02
L8	1193	702/186	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:02
L9	3931	438/14	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:02
L10	1704	438/16	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:02
L11	644	356/32	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:02

## EAST Search History

L12	892	700/110	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:03
L13	2358	700/121	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:03
L14	14	displacement with shape and surface and (semiconductor adj wafer) and differential and ((evaluate) or (evaluation) or (evaluating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:14
L15	12	displacement with shape and surface and (semiconductor adj wafer) and differential and ((evaluate) or (evaluation) or (evaluating)) and processing and ((analyzing) or (analysis) or (analyze))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:21
L16	3	displacement with shape and surface and (semiconductor adj wafer) and (differential with profile) and ((evaluate) or (evaluation) or (evaluating)) and processing and ((analyzing) or (analysis) or (analyze))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:21
L17	2830	250/307	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:18
L18	3033	250/310	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:18
L19	1	displacement with shape and surface and (semiconductor adj wafer) and differential and ((evaluate) or (evaluation) or (evaluating)) and processing and ((analyzing) or (analysis) or (analyze)) and profile.CLM.	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:19
L20	3	displacement with shape and surface and (semiconductor adj wafer) and (differential same profile) and ((evaluate) or (evaluation) or (evaluating)) and processing and ((analyzing) or (analysis) or (analyze))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:21

## EAST Search History

L21	11	displacement with shape and surface and (semiconductor adj wafer) and differential and ((evaluate) or (evaluation) or (evaluating)) and processing and ((analyzing) or (analysis) or (analyze)) and profile and ((calculate) or (calculating) or (calculation) or (calculated))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:28
L22	3	displacement with shape and surface and (semiconductor adj wafer) and differential and ((evaluate) or (evaluation) or (evaluating)) and processing and ((analyzing) or (analysis) or (analyze)) and profile and ((calculate) or (calculating) or (calculation) or (calculated)).CLM.	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:22
L23	57	((displacement with shape) or (measurement with shape) or (measuring with shape)) and surface and (semiconductor adj wafer) and differential and ((evaluate) or (evaluation) or (evaluating)) and profile and ((calculate) or (calculating) or (calculation) or (calculated))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:29
L24	6	((displacement with shape) or (measurement with shape) or (measuring with shape)) and surface and (semiconductor adj wafer) and (differential with profile) and ((evaluate) or (evaluation) or (evaluating)) and ((calculate) or (calculating) or (calculation) or (calculated))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 11:29

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	101	noriaki and semiconductor and surface and displacement	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:44
L2	78	noriaki and semiconductor and surface and displacement and shape	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:44
L3	7	noriaki and semiconductor and surface and displacement and shape and differential and profile	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:46
L4	2	okabe and semiconductor and surface and displacement and shape and differential and profile	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:49
L5	6	okabe and semiconductor and surface and displacement and shape and differential	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:54
L6	2109	substrate with semiconductor and surface and displacement and shape and differential	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:54
L7	2199	substrate with semiconductor and surface and displacement and shape and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:55
L8	9	substrate with semiconductor with surface with displacement and shape and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 14:59
L9	29	substrate with semiconductor with surface with shape and displacement and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:00
L10	1	substrate with semiconductor with surface with shape and displacement and ((differential) or (differentiating)) and ((calculate) or (calculating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:01
L11	0	substrate with semiconductor with surface with shape with displacement and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:01

## EAST Search History

L12	29	substrate with semiconductor with surface with shape and displacement and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:12
L13	1	semiconductor with surface with (shape with evaluating) and displacement and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:13
L14	2	semiconductor with surface with ((shape with evaluating) or (displacement with evaluating)) and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:15
L15	4	semiconductor with surface with ((shape with evaluating) or (displacement with evaluating) or (shape with evaluation) or (displacement with evaluation)) and ((differential) or (differentiating))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:17
L16	4	semiconductor with surface with ((shape with evaluating) or (displacement with evaluating) or (shape with evaluation) or (displacement with evaluation)) and ((differential) or (differentiating)) and ((back) or (front))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:18
L17	2	semiconductor with surface with ((shape with evaluating) or (displacement with evaluating) or (shape with evaluation) or (displacement with evaluation)) and ((differential) or (differentiating)) and ((back) or (front)) and ((memory) or (memorizing) or (store) or (storing) or (stored))	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2006/08/21 15:18